

Replication device and method for reproducing a structure on a substrate

Abstract

5 Replication device (10) for producing nanostructured and/or microstructured components with two assemblies (12, 14) that are moveable in relation to each other, wherein the first assembly (12) has a chuck (18) for receiving a substrate (16) and a second assembly (14) a holder (20) for an imprint structure (22), wherein the assemblies (12, 14) are moveable relative to each other between an
10 imprint position and a loading position, and wherein at least a sealing lip (34, 38) is located on one of the two assemblies (12, 14), said sealing lip (34, 38) facing the other one of the two assemblies and contacting the other one of the two assemblies (12, 14) in the imprint position and radially surrounding the chuck (18) and/or the holder (20), wherein a sealed overpressure chamber (36) between the
15 two assemblies (12, 14) is limited by the sealing lip (34, 38) in the imprint position. Further, also a method for reproducing a structure on a substrate (16) is shown.

Fig. 1